CENTRAL PAR CENTER

MAY 1 1 2006

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Application of: SINGH et al.

Appln No.:

10/082,010

Examiner:

Umez Eronim, Lynette T.

Date Filed:

February 22, 2002

Group:

1765

For:

SLURRY AND METHOD FOR CHEMICAL MECHANICAL POLISHING

OF METAL STRUCTURES INCLUDING REFRACTORY METAL

BASED BARRIER LAYERS

CERTIFICATE UNDER 37 CFR 1.8(1)

I hereby certify that this correspondence addressed to Mail Stop Amendment, Commissioner for Patents is being transmitted via

facsimile No 571-273-8300 on May 11, 2006

Neal R. Jetter

Reg. No 40,803

REPLY TO OFFICE ACTION

Mail Stop Amendment Commissioner for Patents P. O. Box 1450 Alexandria, VA 22313-1450

Sir:

This Reply is responsive to the Office Action mailed January 11, 2006.

Amendments to the Claims are contained in the complete claim listing which appears on pages 2-7 of this document.

Remarks/arguments begin on page 8 of this document.

1